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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/602,488	06/23/2003	Tatyana N. Andryushchenko	42P16161	1128
7590 08/23/2006			EXAMINER	
Todd M. Becker			GURLEY, LYNNE ANN	
BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP Seventh Floor			ART UNIT	PAPER NUMBER
12400 Wilshire Boulevard			2812	
Los Angeles, CA 90025-1026			DATE MAILED: 08/23/2006	

Please find below and/or attached an Office communication concerning this application or proceeding.

<del></del>	Application No.	Applicant(a)				
	Аррисаціон но.	Applicant(s)				
Office Astion Commence	10/602,488	ANDRYUSHCHENKO ET AL.				
Office Action Summary	Examiner	Art Unit				
	Lynne A. Gurley	2812				
The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply						
A SHORTENED STATUTORY PERIOD FOR REPLY WHICHEVER IS LONGER, FROM THE MAILING DA:  Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  If NO period for reply is specified above, the maximum statutory period value of the provision of the provis	ATE OF THIS COMMUNICATION 36(a). In no event, however, may a reply be tim vill apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	I.  lety filed  the mailing date of this communication.  D (35 U.S.C. § 133).				
Status						
1) Responsive to communication(s) filed on <u>08 Au</u>	ugust 2006.	·				
2a) This action is <b>FINAL</b> . 2b) ☑ This	This action is <b>FINAL</b> . 2b)⊠ This action is non-final.					
3) Since this application is in condition for allowar	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is					
closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.						
Disposition of Claims		,				
4)⊠ Claim(s) <u>1-22 and 34-44</u> is/are pending in the application.						
4a) Of the above claim(s) is/are withdrawn from consideration.						
5) Claim(s) is/are allowed.						
6)⊠ Claim(s) <u>1-22 and 34-44</u> is/are rejected.						
7) Claim(s) is/are objected to.						
8) Claim(s) are subject to restriction and/o	r election requirement.					
Application Papers						
9) The specification is objected to by the Examine	r.					
10)⊠ The drawing(s) filed on <u>22 March 2004</u> is/are: a)⊠ accepted or b)□ objected to by the Examiner.						
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).						
11) The oath or declaration is objected to by the Ex	caminer. Note the attached Office	Action or form PTO-152.				
Priority under 35 U.S.C. § 119						
12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of:						
1. Certified copies of the priority documents have been received.						
2. Certified copies of the priority documents have been received in Application No						
3. Copies of the certified copies of the priority documents have been received in this National Stage						
application from the International Bureau	, , , , , , , , , , , , , , , , , , , ,	1 -				
* See the attached detailed Office action for a list of the certified copies not received.						
		LYNNE A. GURLEY				
	• • • • • • • • • • • • • • • • • • • •	MARY PATENT EXAMINER				
Attachment(s)		TC 2800, <b>AU 2812</b>				
<ol> <li>Notice of References Cited (PTO-892)</li> <li>Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> </ol>	4) Interview Summary Paper No(s)/Mail Da					
3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)  5) Notice of Informal Patent Application (PTO-152)						
Paper No(s)/Mail Date	6)  Other:					

## **DETAILED ACTION**

This Office Action is in response to the RCE with amendment, and remarks filed 8/8/06. Currently, claims 1-22 and 34-44 are pending.

## Continued Examination Under 37 CFR 1.114

1. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 8/8/06 has been entered.

## Claim Rejections - 35 USC § 103

- 1. The factual inquiries set forth in *Graham* v. *John Deere Co.*, 383 U.S. 1, 148 USPQ 459 (1966), that are applied for establishing a background for determining obviousness under 35 U.S.C. 103(a) are summarized as follows:
  - 1. Determining the scope and contents of the prior art.
  - 2. Ascertaining the differences between the prior art and the claims at issue.
  - 3. Resolving the level of ordinary skill in the pertinent art.
  - 4. Considering objective evidence present in the application indicating obviousness or nonobviousness.
- 2. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later

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invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

3. Claims 1-22 and 34-44 are rejected under 35 U.S.C. 103(a) as being unpatentable over Uzoh et al. (US 6,780,772, dated 8/24/04, filed 12/21/01) in view of Jorne et al. (US 2004/0072423, dated 4/15/04, filed 1/14/02) and further in view of Wytman (US 6,764,713, dated 7/20/04, filed 4/4/01).

Uzoh shows the method substantially as claimed, in figures 1-9 and corresponding text, as providing a wafer 202 (fig. 4), the wafer comprising an inter-layer dielectric (ILD) 210 having a feature therein 204 (fig 4; column 4, lines 50-61), an underlayer 208 (the first layer of the multi-layered barrier layer; column 4, lines 61-67) deposited on the ILD, a barrier layer 208 (remaining layers of the multi-layered barrier layer) deposited on the under-layer and a conductive layer 206 (Cu; column 5, lines 1-4) deposited on the barrier layer; exposing the barrier layer (Fig. 9A) and removing the barrier layer (fig. 9B). The removal of the barrier layer and the conductive layer is performed by electropolishing (column 8, lines 37-67; column 9, lines 1-7). The conductive layer is copper. The barrier comprises tantalum (Ta). The underlayer is TaN. A portion of the under-layer and/ or the conductive layer may be removed using CMP (column 8, lines 37-67; column 9, lines 1-7).

Uzoh lacks anticipation only in not explicitly teaching the specifics of the electropolishing process, i.e.: 1) that the wafer is placed in a holder that seals the edges thereof; 2) that the wafer is placed in an electrolyte, such that at least the barrier layer is immersed in the electrolyte; and an electrical potential is applied between the wafer and an electrode immersed in the electrolyte until at least part of the barrier layer is removed; 3) the electrolyte has a pH equal

to or greater than 10; 4) the electrolyte comprises a solution of KOH, NaOH, NH4OH or TMAH; 5) an additive is added to the electrolyte; 6) the additive is an oxidizer, a corrosion inhibitor, a surfactant, a buffer, a complexor or combinations thereof; and 7) the electric potential has a value equal to or greater than 0.5V with respect to the saturated calomel reference electrode.

Wytman teaches an apparatus which can be used for electropolishing techniques which seals the edges of the wafer (figure 5 and corresponding text).

Jorne teaches an electropolishing apparatus used to remove conductive layers from a substrate with an electrolytic solution and an applied voltage. Submersion into an electropolishing solution or electrolytic solution is taught [0014], [0079], [0092], [0011]-[0012] for the removal of any excess metal layers on the substrate surface outside the contact). Additives to the electrolyte are discussed in order to keep the electrolyte the proper consistency (column 7, lines 8-30).

It would have been obvious to one of ordinary skill in the art to have used the wafer chuck taught in Wytman, which seals the edges of the wafer, with the motivation that Wytman teaches that sealing the edge of the wafer is conventional. O-rings are also taught for this purpose (background).

It would have been obvious to one of ordinary skill in the art to have placed the wafer in an electrolyte, such that at least the barrier layer is immersed in the electrolyte; and to have applied an electrical potential between the wafer and an electrode immersed in the electrolyte until at least part of the barrier layer is removed, in the method of Uzoh, as taught by Jorne, with the motivation that Uzoh uses an electropolishing method to remove the barrier and the conductive layers, while Jorne teaches the electropolishing apparatus for the same purpose and,

additionally, teches immersion of the conductive layers in the electrolyte and the applied electrical potential between the wafer and an electrode immersed in the electrolyte in order to remove of the conductive layers.

It would have been obvious to one of ordinary skill in the art to have had the electrolyte have a pH equal to or greater than 10; to have had the electrolyte comprise a solution of KOH, NaOH, NH4OH or TMAH; to have added an additive to the electrolyte; to have had the additive be an oxidizer, a corrosion inhibitor, a surfactant, a buffer, a complexor or combinations thereof; and to have had the electric potential have a value equal to or greater than 0.5V with respect to the saturated calomel reference electrode, in the method of Uzoh, as supported by Jorne, with the motivation that these are all conventional additives which adjust the rate and efficiency of removal in a conductor removal process (i.e. CMP), especially in the absence of any showing of criticality and, with the motivation that Jorne teaches the modification of the electrolyte by various means to keep a desired consistency to optimize the process and adapt the process to different conductive layers [0011], [0025], [0031]-[0032], [0083], [0093]. Additionally, the electropolishing process may be optimized to control any varying local electric fields by changing the voltage applied, the additives which can act as plating suppressors or antisuppressors to modulate the electropolishing (See Cox, US 6,383,917 cited in the PTO Form 892; column 4, lines 48-60).

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Lynne A. Gurley whose telephone number is 571-272-1670. The examiner can normally be reached on M-F 7:30-4:00.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Michael Lebentritt can be reached on 571-272-1873. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Lynne A. Gurley
Primary Patent Examiner

TC 2800, Art Unit 2812

LAG August 20, 2006